

# INFORMATION DISCLOSURE CITATION

OMB No. 0651-0011

Atty. Docket No.	3180.0285	Appln. No.	09/931,916
Applicant	Mitsutake et al.		
Filing Date	August 20, 2001	Group:	2857

## U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate

## FOREIGN PATENT DOCUMENTS

	Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
MCB	1207531	2/10/99	China			Abstract

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)


Examiner <i>Nancy Catherine Baran</i>	Date Considered <i>10/13/04</i>
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Atty. Docket No. 03180.0285		Serial No. Not Yet Assigned					
Applicant Kunihiro MITSUTAKE et al.							
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<b>U.S. PATENT DOCUMENTS</b>							
Examiner Initial*		Document Number	Date	Name	Class	Sub Class	Filing Date If Appropriate
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		Document Number	Date	Country	Class	Sub Class	Translation Yes or No
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
MCB		IKOTA, M. et al., "Discrimination of Clustered Defects on Wafers Using Statistical Methods", Proc. 1997 Second Int. Workshop Statistical Metrology, pp. 52-55.					
Examiner Mary Catherine Brown				Date Considered 2/7/04			
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